



**AMENDMENT UNDER CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 1746**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:	Confirmation No.: 7420
Takaei SASAKI et al.	Group Art Unit: 1746
Serial No.: 10/706,944	Examiner: Michail Kornakov
Filed: November 14, 2003	Attorney Docket No.: 101136-00103

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS AND METHOD FOR THE PREPARATION THEREOF, AND SEMICONDUCTOR CIRCUITS AND METHOD FOR THE FABRICATION THEREOF

**AMENDMENT UNDER 37 CFR §1.116**

**Mail Stop: AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Date: December 23, 2004

Sir:

In reply to the outstanding Office Action dated September 3, 2004, the period for response being extended one-month from December 3, 2004, to January 3, 2004, with the filing of the attached Petition for Extension of Time, please amend the application as shown on the following pages: